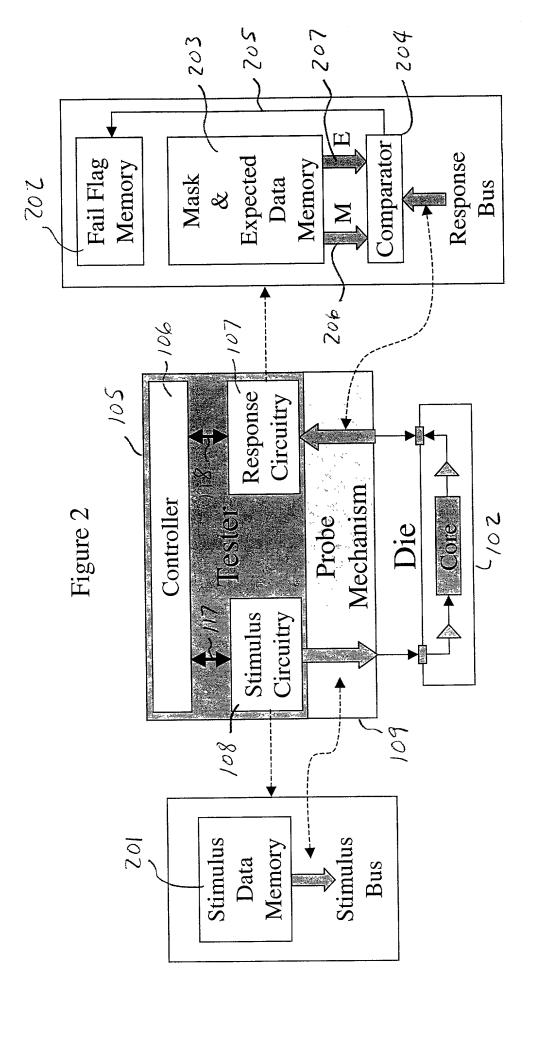
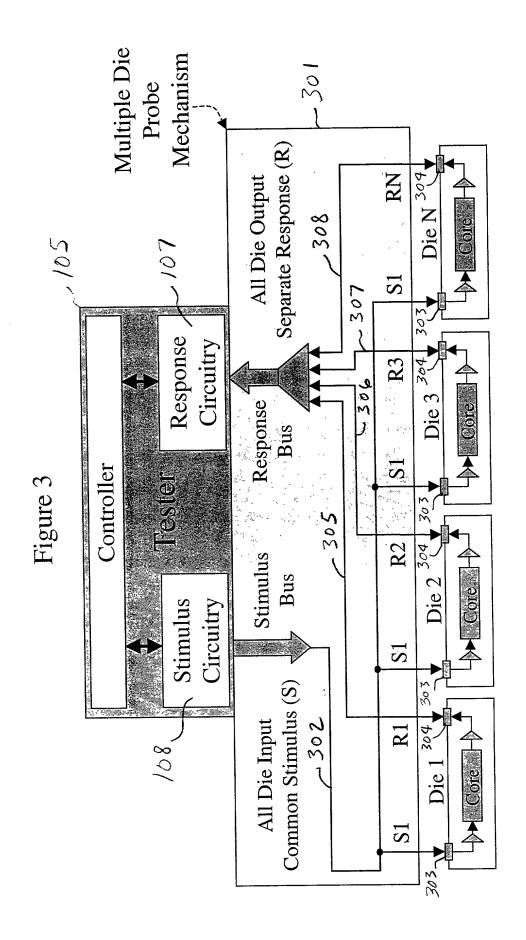
Bus Response Needles Probe 601 Output
Pad Response Circuitry ~211 7 Mechanism Figure 1C Controller Buffers Probe Die Stimulus Circuitry Pad (115) Input ,80/ Stimulus Bus 701 Figure 1B Figure 1A * Wafer Ψķ Die E M x 豑 緣 104

Stimulus & Response Circuitry

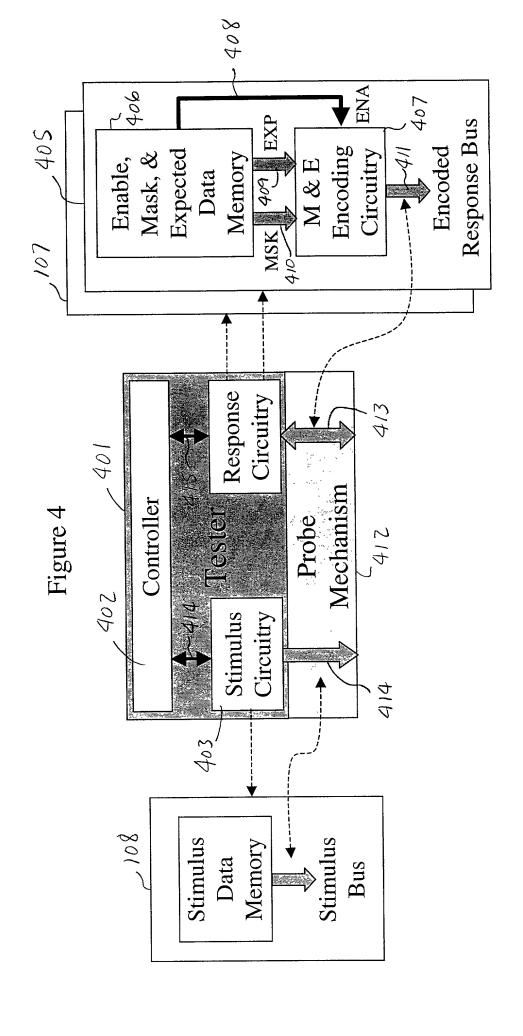
Conventional Tester





(Sum of R1-RN) <= (Tester Response Bus Width)

Adapting Testers To Support Improved Wafer Testing



OSOSHOV OSISSI

Mask & Expected Encoding Circuitry

Figure 5A

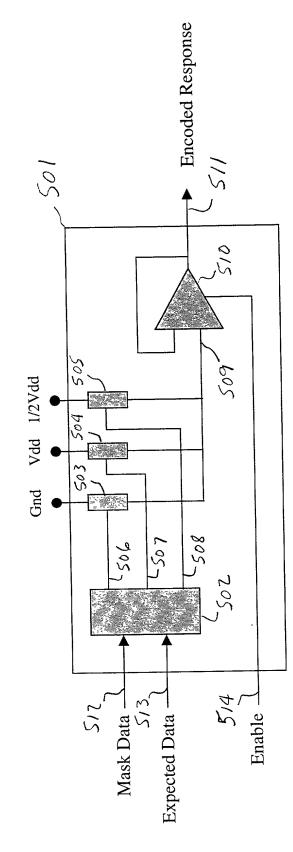
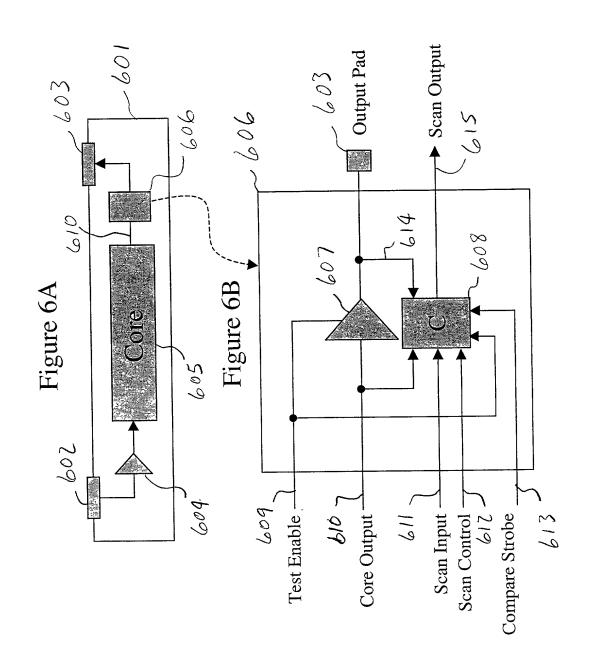


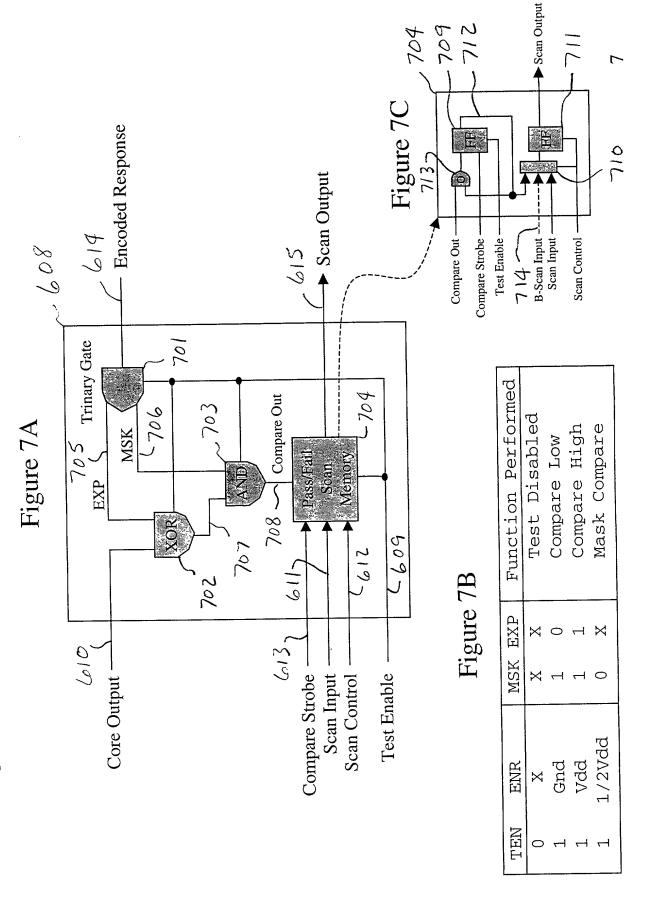
Figure 5B

Output Mode	Disabled	Low	High	Mask
ENR	Z	Gnd	Vdd	1/2Vdd
EXP	0	0		×
MSK	0	0	0	\leftarrow I
ENA	0	\leftarrow 1	ᆏ	⊣

Adapting Die 2-State Outputs To Support Improved Wafer Testing



Maskable Comparator For 2-State Outputs



Trinary Gate Circuit Example

Figure 8A

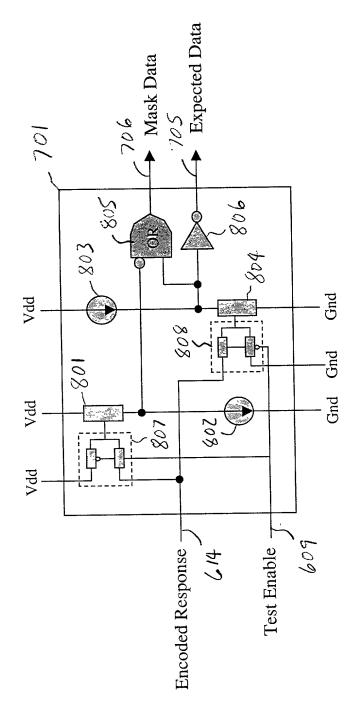
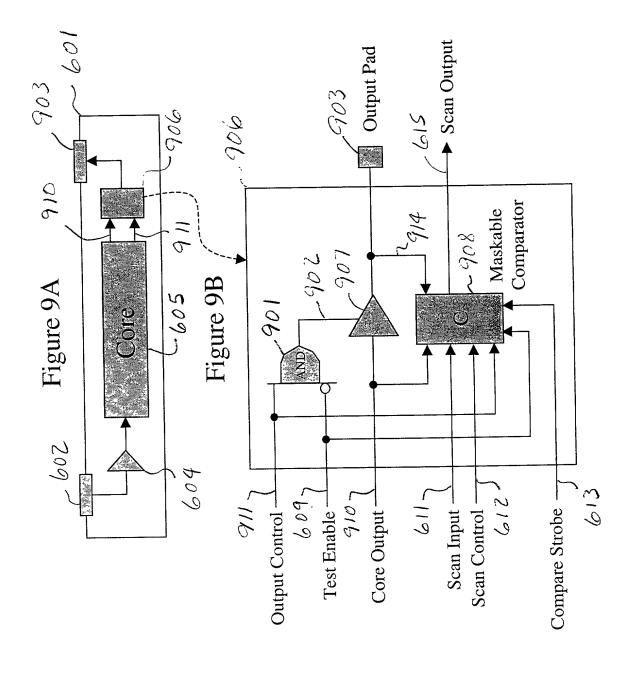


Figure 8B

Adapting Die 3-State Outputs To Support Improved Wafer Testing



Maskable Comparator For 3-State Outputs

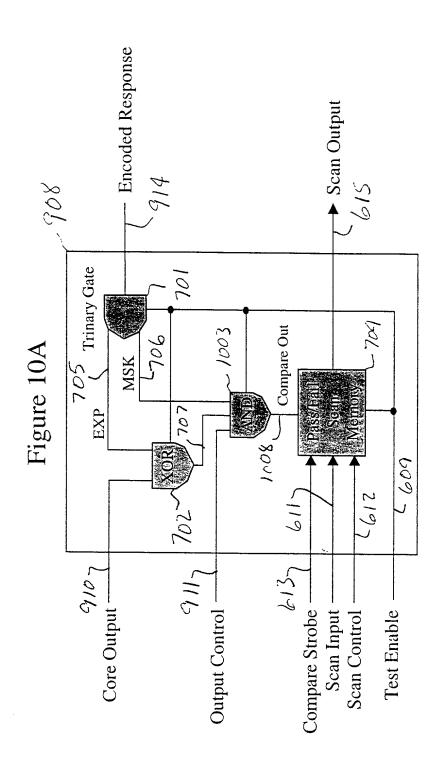
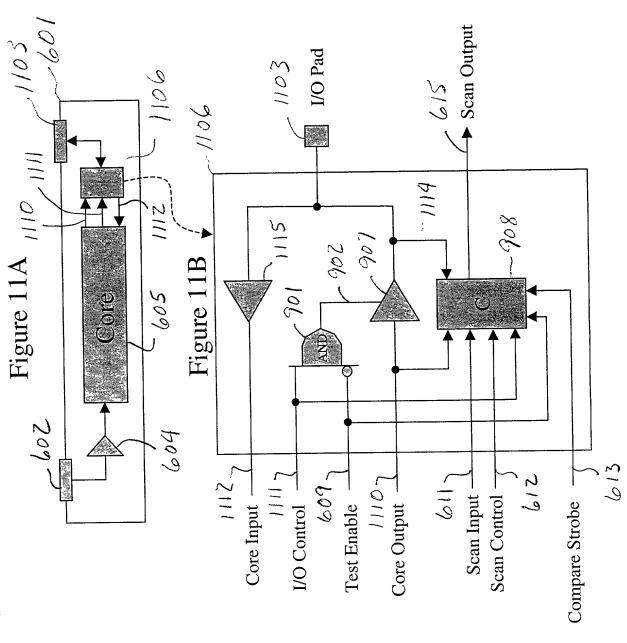


Figure 10**8**

Function Performed	Test Disabled	Compare Low	Compare High	Mask Compare	Test Output Control
EXP	×	0	\vdash	×	0/1
MSK	×	\leftarrow	⊣	0	\vdash
ENR	×	Gnd	Vdd.	1/2Vdd	Gnd/Vdd
TEN	0	Н	T	↤	\vdash
OC	×	\vdash	₩	\leftarrow	0

Adapting Die Input/Outputs To Support Improved Wafer Testing



Maskable Comparator For Input/Outputs

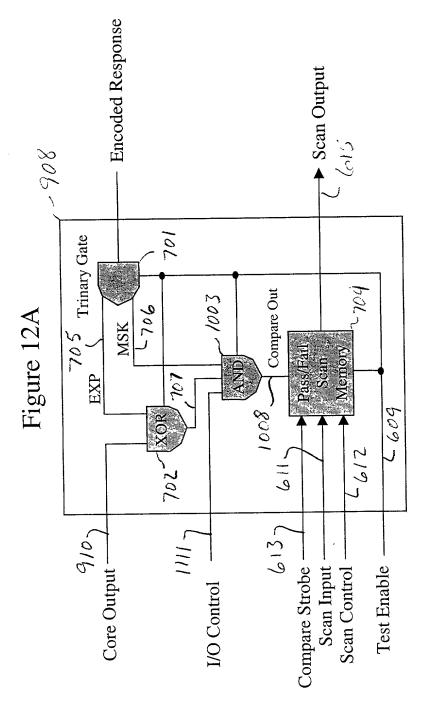
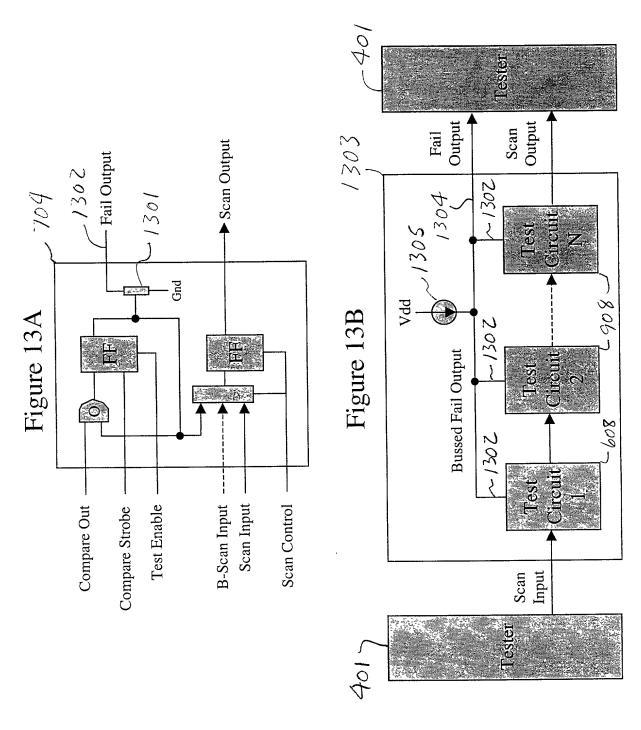


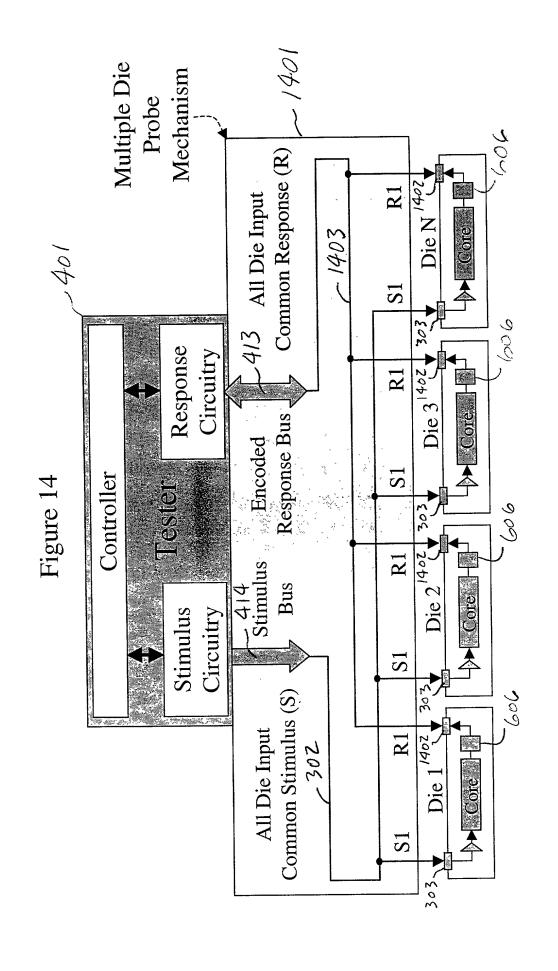
Figure 12B

							_
Function Pertormed	Test Disabled	Compare Low	Compare High	Mask Compare	Test I/O Control	Input Stimulus	
MSK EXP	×	0	Н	×	0/1	0/1	
MSK	×	\leftarrow	\vdash	0	\vdash	Н	
ENR	×	Gnd	Vdd	1/2Vdd	Gnd/Vdd	Gnd/Vdd	
TEN	0	Н	⊣	\vdash	\vdash	\vdash	
JOI	×	⊣	Н	\leftarrow I	0	0	

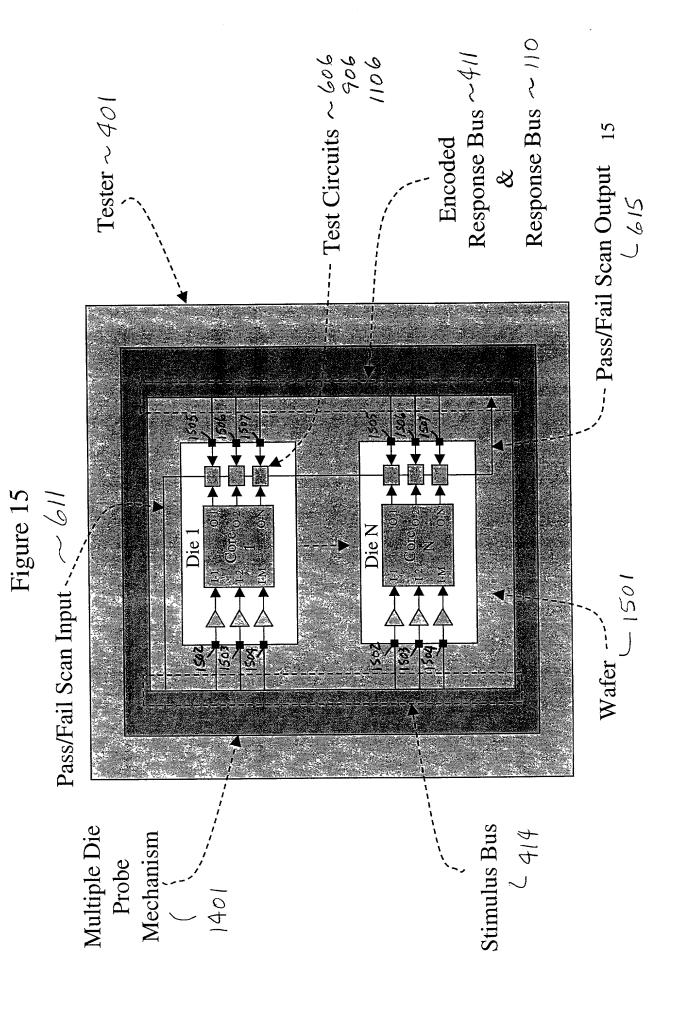
Fail Output for Diagnostic Testing



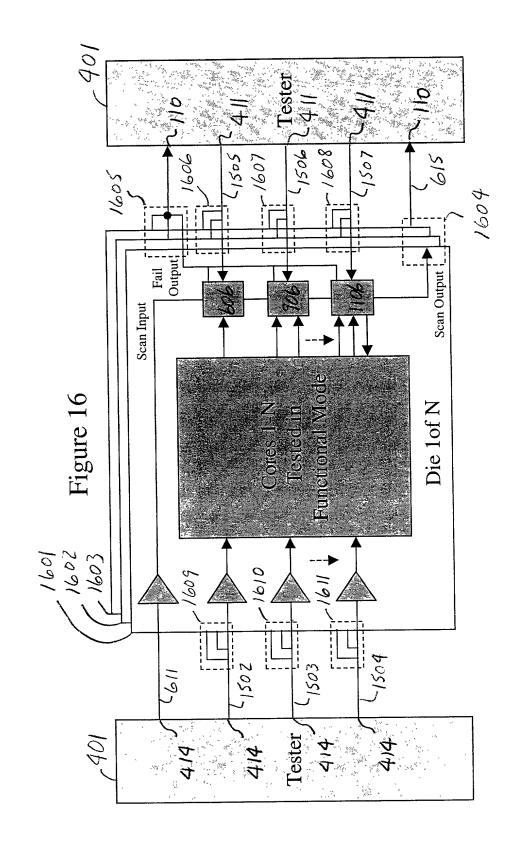
Improved Multiple Die Probe Test Example



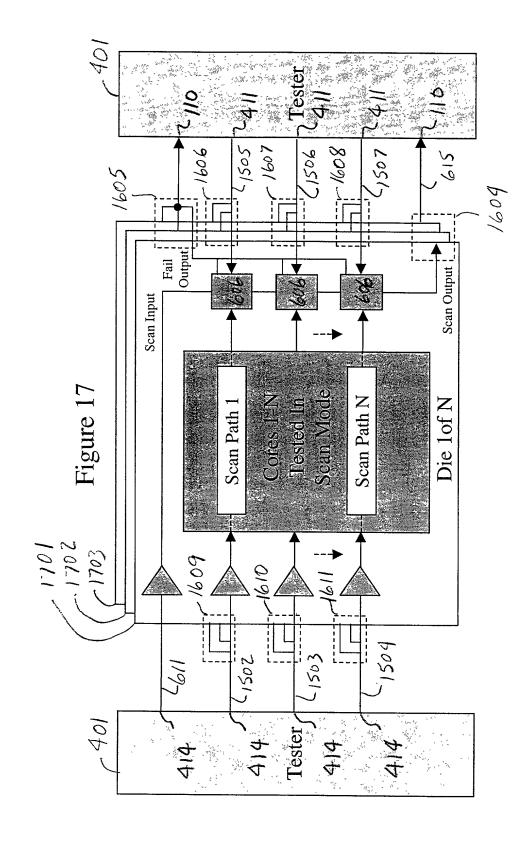
Conceptual View of Improved Die Test



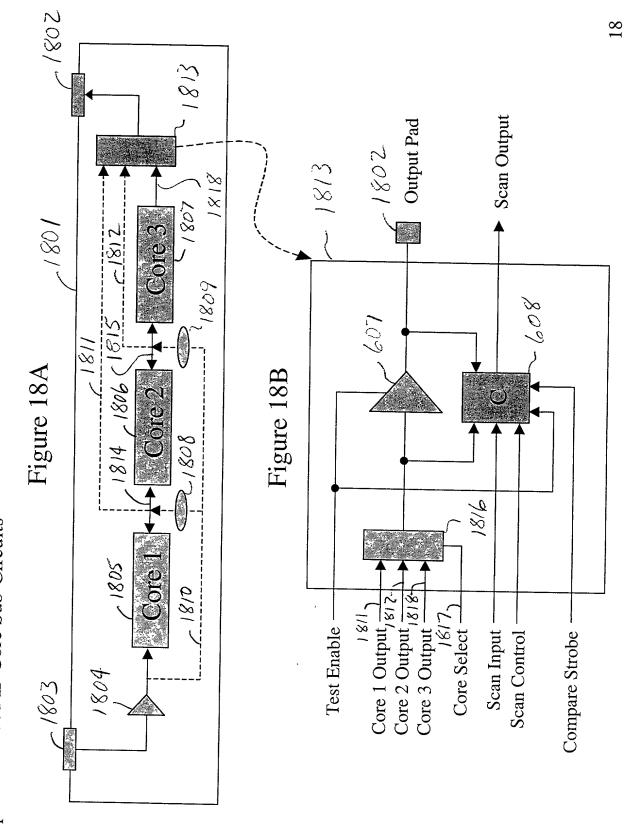
Die Being Tested in Functional Mode



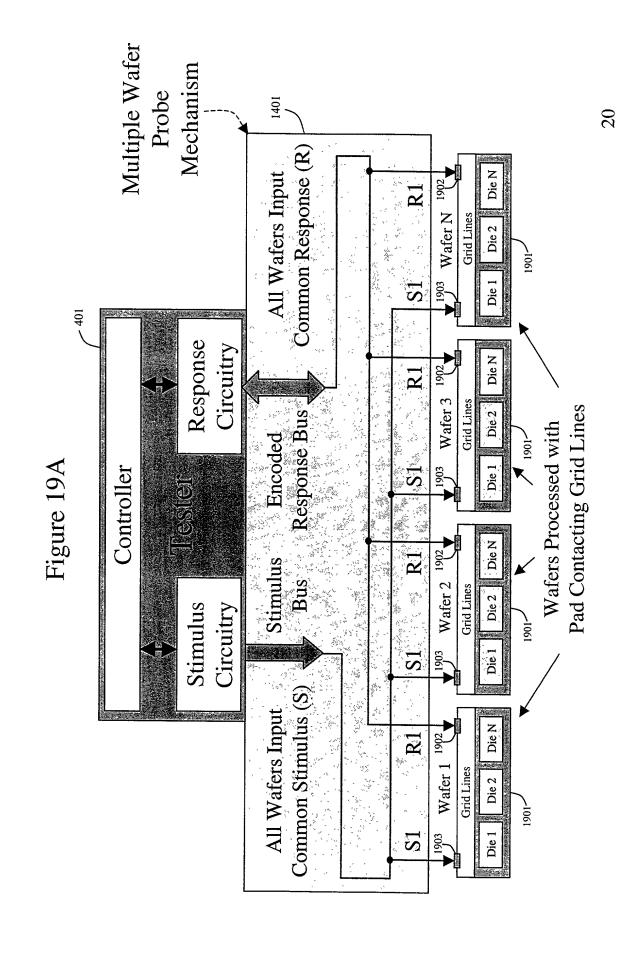
Die Being Tested in Scan Mode

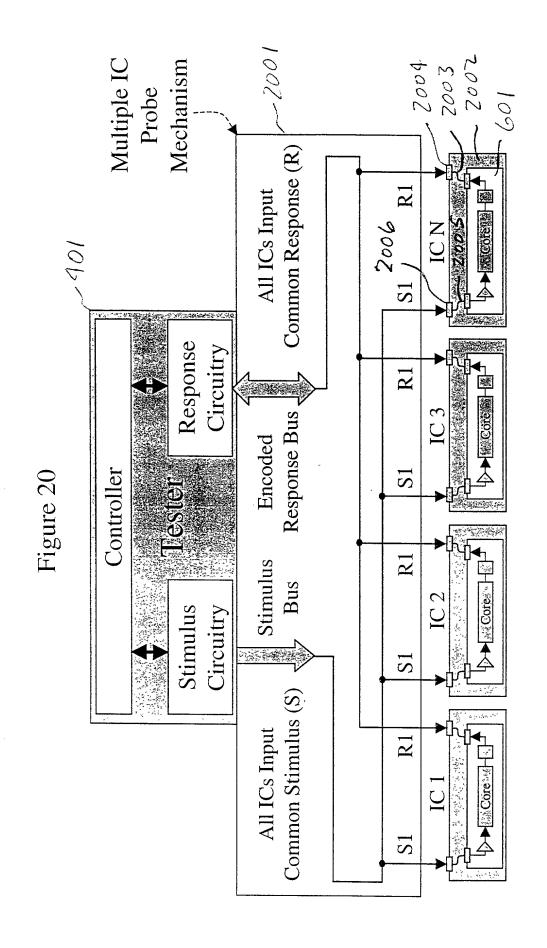


Testing System-On-Chip Die having Multiple Embedded IP Core Sub-Circuits



Pad Contacting Grid Lines Wafer Processed with 1910 RI Pad Fuse Die N R1 Grid Line Probe Contact SI 2061 1909 Response Circuitry R_1 RI Response Bus Die 3 -Grid Lines-Encoded Needles Controller Figure 19 8061 Stimulus **R1** 1904 Bus Stimulus Die 2 Circuitry SI \$ S1 Probe Contact S1 Grid Line 0~1906 1907 Pad Contacts R1 Die 1 SI





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